



MEMS Ultrasonic Transducers

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Message from the Guest Editors

Dear Colleagues,

Ultrasonic transducers are widely used in medical imaging, industrial non-destructive testing, ultrasonic microscopes, ultrasonic radars, underwater ultrasound, ultrasonic measurement, and other fields. MEMS ultrasonic transducers are expected to push the application of ultrasound technology to a new level, realizing its application in emerging fields such as smartphones, automotive electronics, smart homes, autonomous driving, robotics, and medical devices.

In this Special Issue, original research articles and reviews are welcome. Research areas may include (but not limited to) the following:

- Piezoelectric micromachined ultrasonic transducers (PMUT);
- Capacitive micromachined ultrasonic transducers (CMUT);
- Micromachined ultrasonic transducers;
- Thin-film transducers;
- MEMS vector hydrophones;
- MEMS pressure sensors;
- MEMS transducer structure design and simulation;
- Micromachined 1-3 piezocomposite;
- Applications of MEMS transducers.

We look forward to receiving your contributions.





Editor-in-Chief

Message from the Editor-in-Chief

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